

**METHOD FOR FORMING A READ TRANSDUCER BY ION MILLING AND  
CHEMICAL MECHANICAL POLISHING TO ELIMINATE NONUNIFORMITY  
NEAR THE MR SENSOR**

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**ABSTRACT**

A method for forming a read transducer by ion milling and chemical mechanical polishing to eliminate nonuniformity near the MR sensor is disclosed. The resist mask is eliminated in the read transducer formation process so that the thickness of the layers near the read transducer has a uniform thickness.